AMENDMENTS TO THE SPECIFICATION

Please replace paragraphs **[0013], [0016], [0018], [0022], [0026], [0029], [0031], [0033], [0048], [0051], [0070], [0082], [0089]** and **[0097]** with the following amended paragraphs:

[0013] FIG. 1(a) ~~shows~~ and FIG. 1(b) show the structure of a three-dimensional measure device of a first embodiment;

[0016] FIG. 4(a) ~~illustrates~~ and FIG. 4(b) illustrate the operation of the CCD sensor;

[0018] FIG. 6(a) ~~illustrates~~ and FIG. 6(b) illustrate the operation of a MOS-type sensor;

[0022] FIG. 10(a) ~~shows~~ and FIG. 10(b) show a second modification of the control;

[0026] FIG. 14(a) ~~shows~~ and FIG. 14(b) show a third modification of the control;

[0029] FIG. 17(a) ~~shows a modification~~ and FIG. 17(b) show modifications of the optical system;

[0031] FIG. 19(a) ~~illustrates~~ and FIG. 19(b) illustrate the measurement principle of the short distance mode;

[0033] ~~FIG. 1 shows~~ FIGS. 1(a) and 1(b) show the structure of a three-dimensional measure - device of the first embodiment. ~~Part~~ FIG. 1(a) shows the entire structure, and ~~part~~ FIG. 1(b) shows the structure of the image sensing surface.

[0048] ~~FIG. 4 illustrates~~ FIGS. 4(a) and 4(b) illustrate the operation of a CCD sensor. ~~Part~~ FIG. 4(a) schematically shows the structure, and ~~part~~ FIG. 4(b) shows the control timing. The state of each time t0, t1, t2, t3, t4 is described below.

[0051] ~~FIG. 6 illustrates~~ FIGS. 6(a) and 6(b) illustrate the operation of a MOS-type sensor. ~~Part~~ FIG. 6(a) summarizes the structure, ~~part~~ FIG. 6(b) shows the movement of the electric charge, and ~~part~~ FIG. 6(c) shows the control timing. The state times t0, t1, t2, t3, t4 is described below.

t0: Load starts accumulating at PD incidental capacitor C1.

t1: Gate ST switches ON, and the electric charge is transferred from incidental capacitor C1 to a sufficiently large capacity condenser C2.

t2: Gate ST switches OFF, and again electric charge starts accumulating in incidental capacitor C!.

t3: Gate RS switches ON, and the accumulated electric charge is discharged from the incidental capacitor C1 to the power line Vcc at periods t2-t3.

t4: Gate RS switches OFF, and electric charge again starts accumulating.

[0070] ~~FIG.~~ FIGS. 10(a) ~~shows~~ and 10(b) show a second modification of the control.

[0082] When measuring long distance as described above, it is possible to increase resolution to achieve high accuracy measurement by shifting the exposure timing between frames so

as to have the exposure period of each frame shorter than the emission time as shown in ~~FIG.~~ FIGS. 14(a) and 14(b), and perform a plurality of exposures in the emission period (pulse light projection period) with the assumed appearance of simultaneously of a plurality of frames. In the example shown in ~~FIG.~~ FIGS. 14(a) and 14(b) the distance data of frame (n) representing the rise time difference D11 and the distance data of frame (n+3) representing the fall time difference D11' are used to determine the distance value.

[0089] ~~FIG.~~ FIGS. 17(a) and 17(b) ~~shows~~ show modifications of the optical system. Structural elements of the example in ~~this drawing~~ these drawings are designated by symbols identical to those of ~~FIG.~~ FIGS. 1(a) and 1(b) .

[0097] ~~FIG.~~ FIGS. 19(a) and 19(b) ~~illustrates~~ illustrate the measurement principle of the near-field mode.